

Impurity monitor

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1. Purpose / Application

- [1] Monitoring impurity behaviors
- [2] Signal supply to ECH power control system during long pulse discharges

2. Name of analysis (Kaiseki) data / module of MyView2

imp01, imp02

3. General Description (Port, field line, time resolution, spatial resolution, number of channels, etc.)

3.1. 20cm normal incidence monochromators with SEM (see Fig. 1)

- Ly α , CIII, CIV, OV, OVI

Time resolution: $\Delta t=0.1\text{ms}$

Observation area: $1\text{m}^V \times 0.2\text{m}^H$

3.2. Grazing incidence monochromator with SEM

- FeXVI

Time resolution: $\Delta t=0.1\text{ms}$

Observation area: $0.2\text{m}^V \times 0.1\text{m}^H$

3.3. Interference filter + photomultipliers (or + APD)

- H α , HeI (two systems for low- and high-density discharges)

Time resolution: $\Delta t=0.1\text{ms}$

Observation area: $1.2\text{m}^V \times 0.2\text{m}^H$

3.4. Others

- 20cm normal incidence spectrometers with CCD
- EUV spectrometers with CCD
- Radiation loss (SEM)

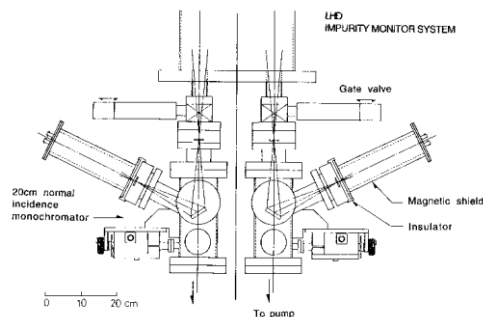


Figure 1 20cm VUV spectrometers for impurity monitor.

Port assembly: #10-O port (see Fig. 2)

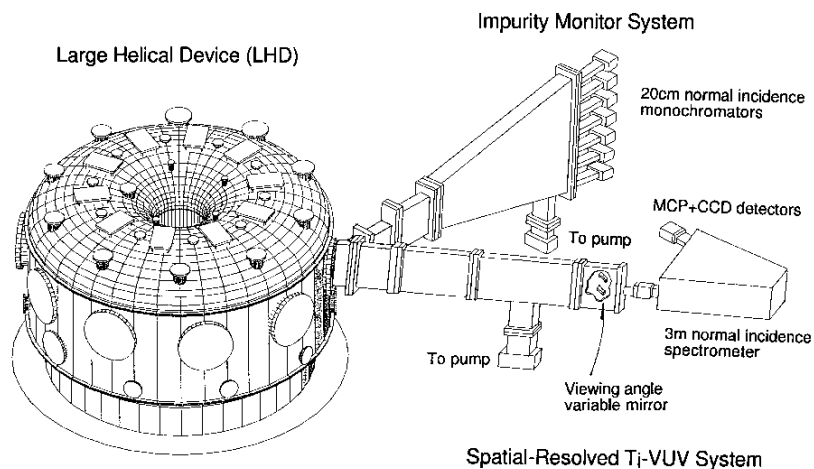


Figure 2 20cm VUV spectrometers for impurity monitor.

4. Requirement in use

- Before experiment: opening swing and gate valves, turning on power supply and setting CCD parameters
- After experiment: closing valves and turning off power supply

5. Description of analysis (Kaiseki) data / module of MyView2

- imp01

DimNo = 1

DimName = 'Time'

DimSize = 12001

ValNo = 3

ValName = 'CIII','OV','none'

- imp02

DimNo = 1

DimName = 'Time'

DimSize = 1310

ValNo = 6

ValName = 'CIV', 'OVI', 'HI', 'FeXVI', 'CIII', 'OV'

6. Others

- Typical examples of CIII, OV and FeXVI from impurity monitor

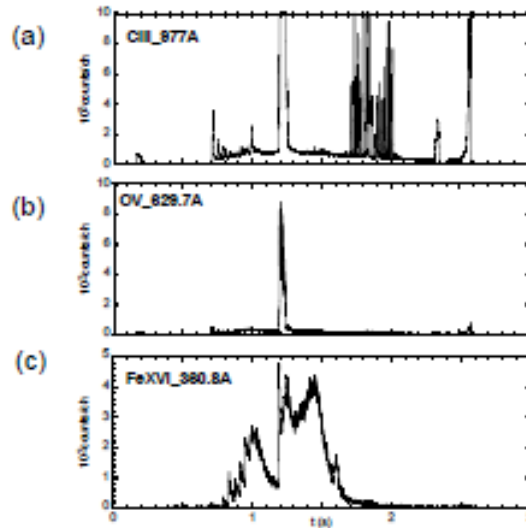


Figure 3 Typical examples of (a) CIII, (b) OV and (c) FeXVI from impurity monitor.

References

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- and others